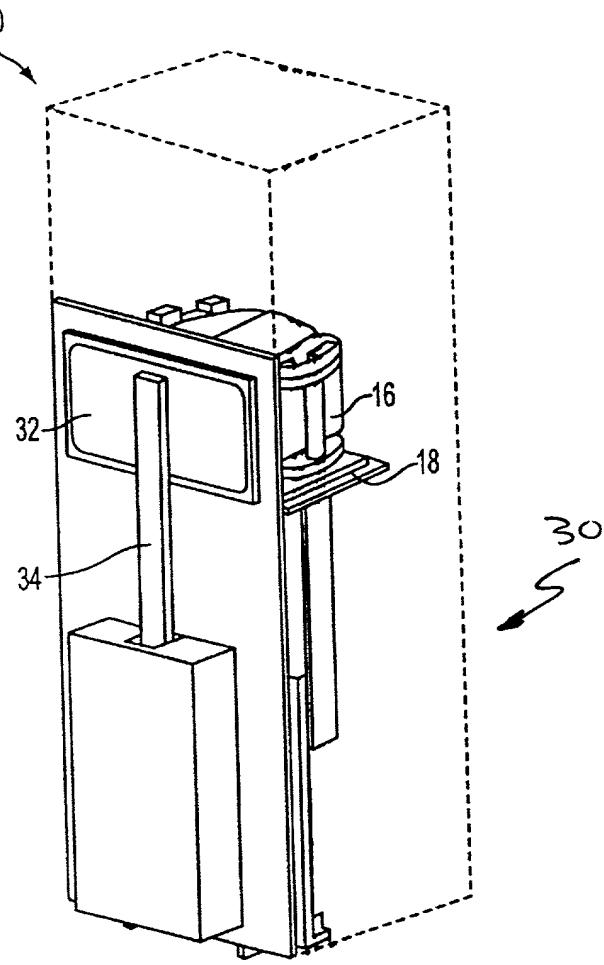


**FIG. 1A**  
**(PRIOR ART)**



**FIG. 1B**  
(PRIOR ART)

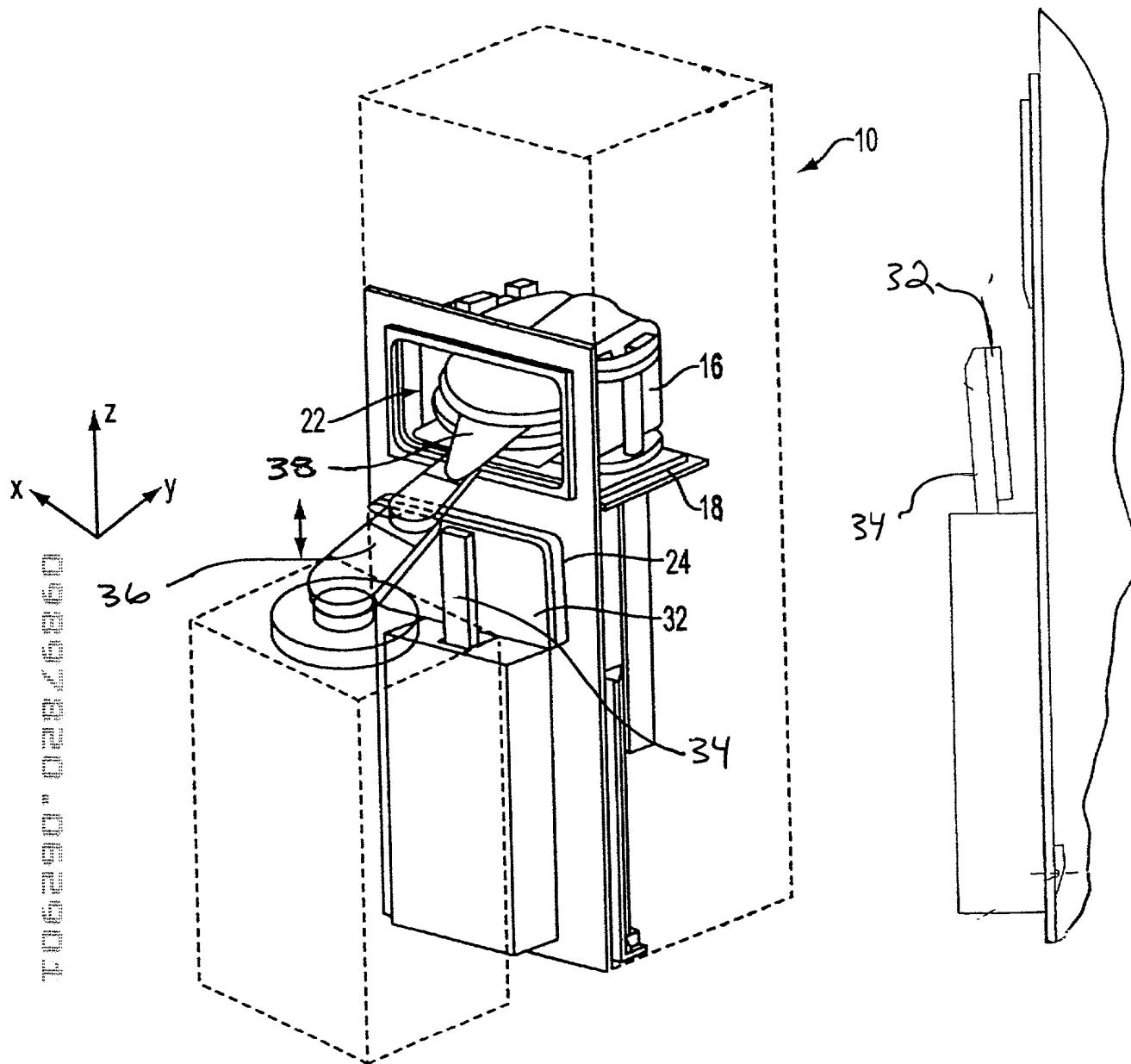


FIG. 1C  
(PRIOR ART)

FIG. 1D  
(PRIOR ART)

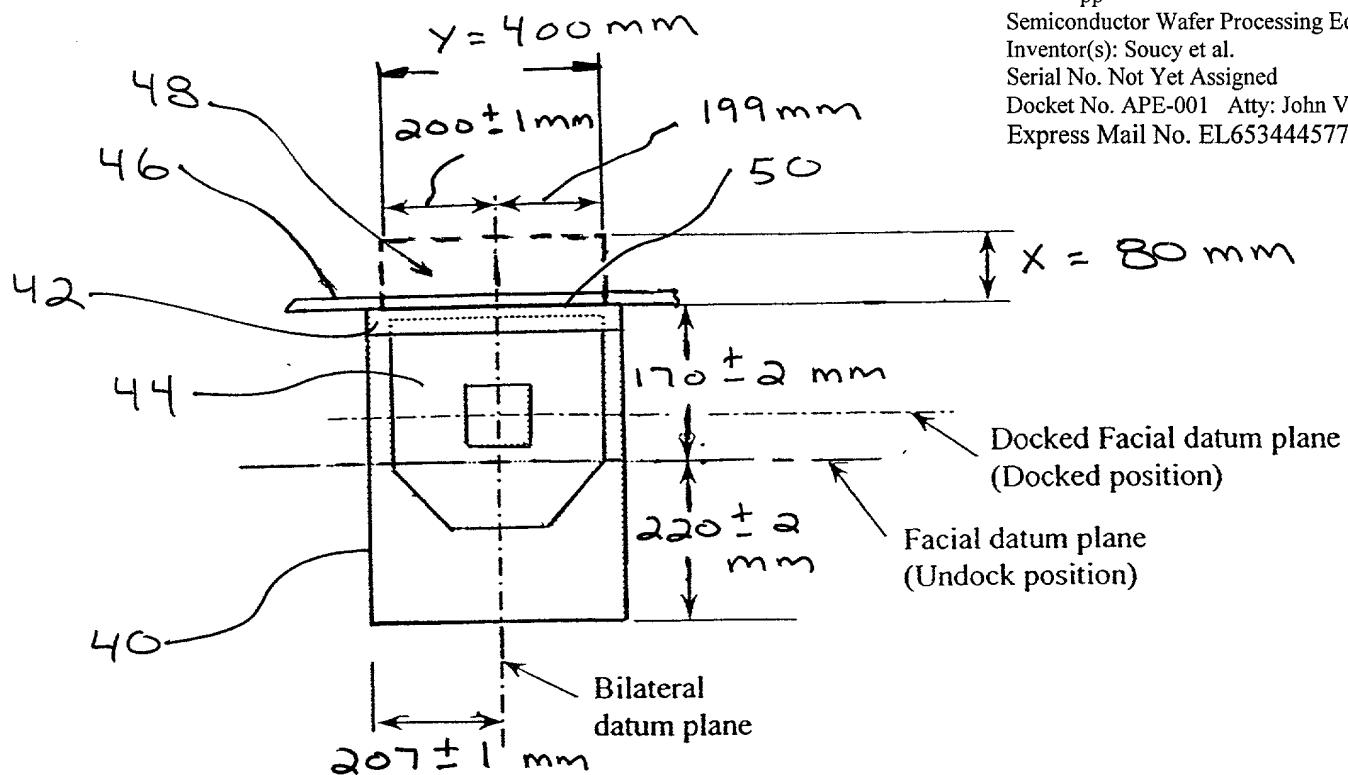


FIG. 2A

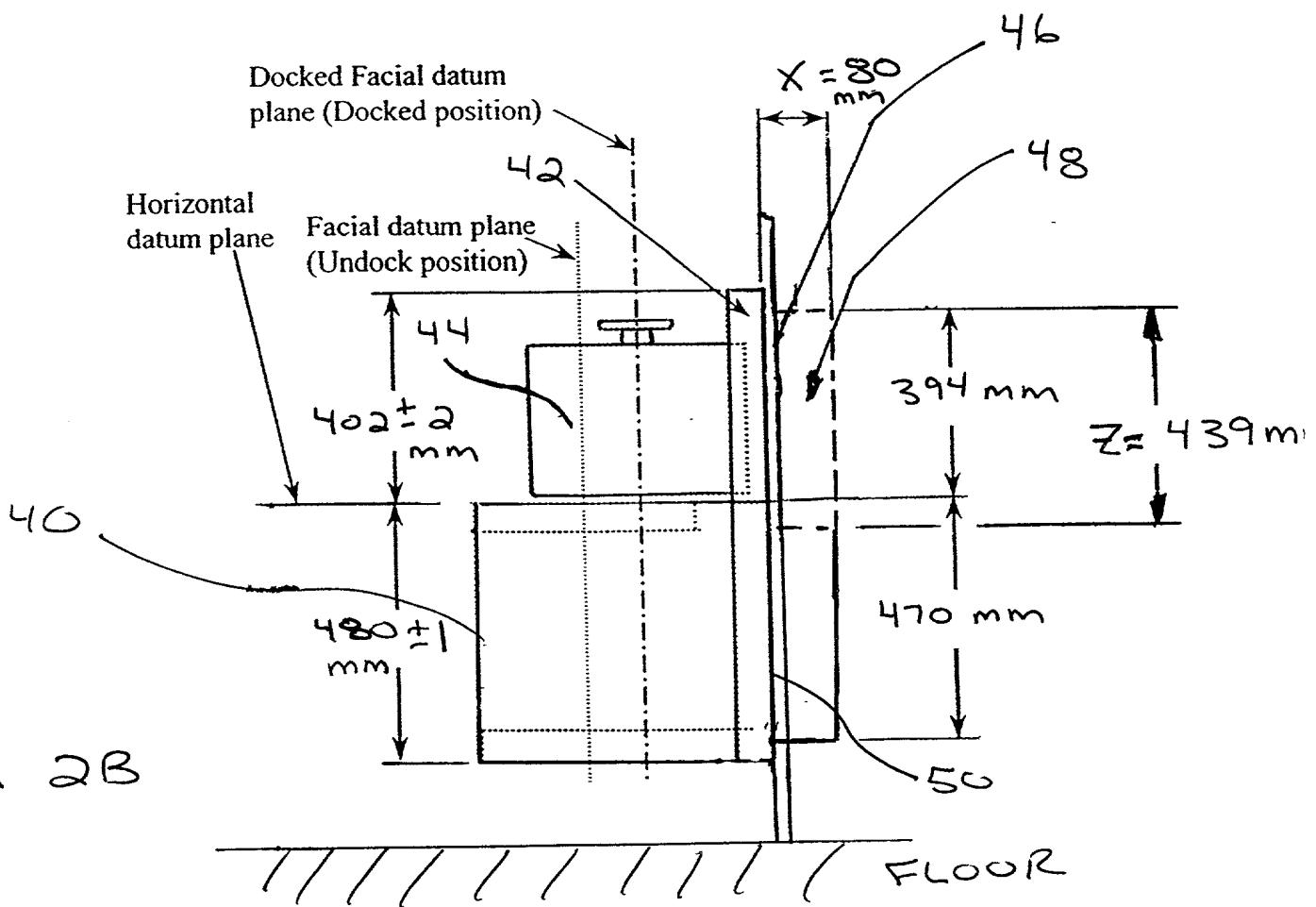
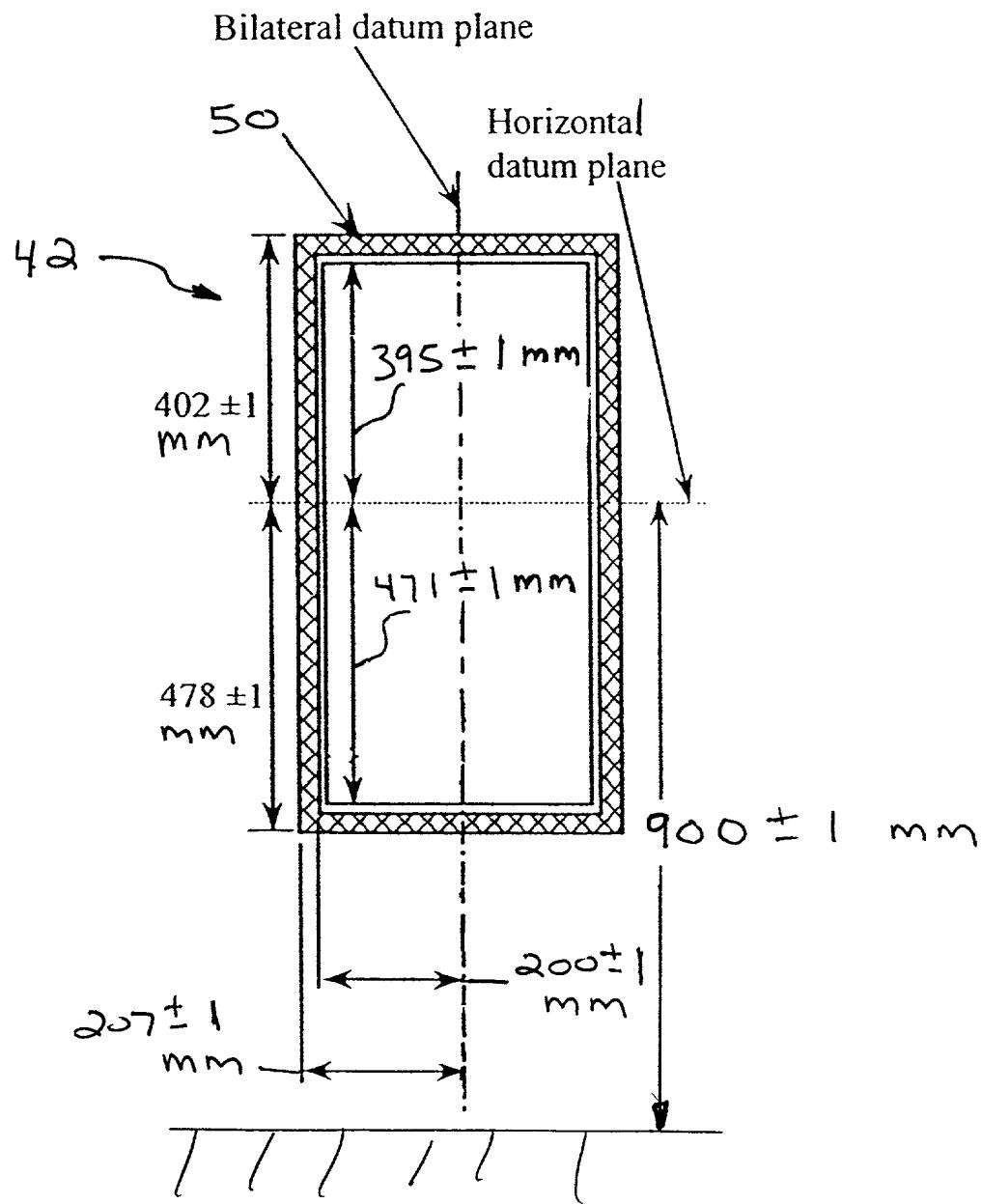


FIG. 2B



FLOOR

FIG. 2C

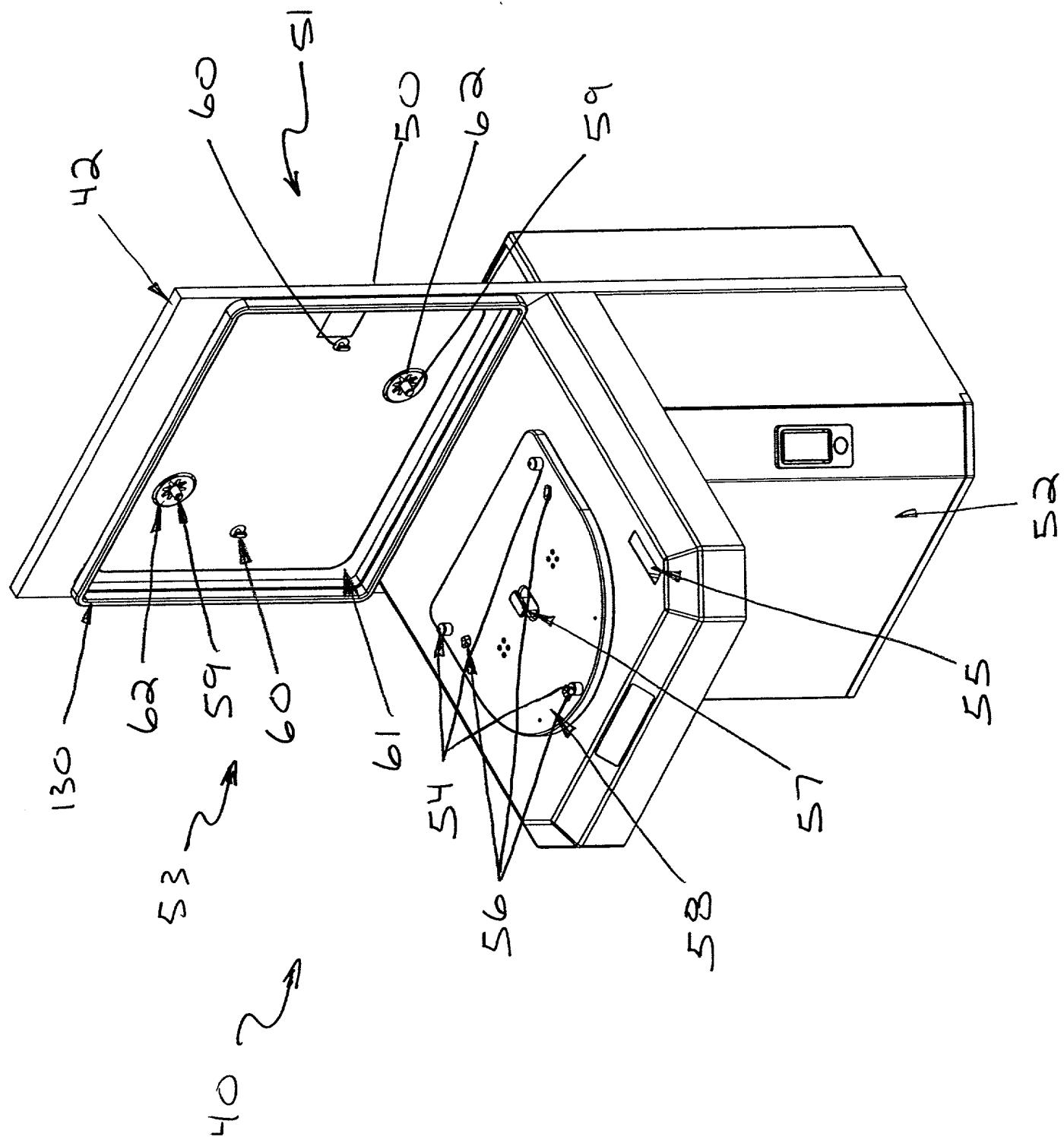
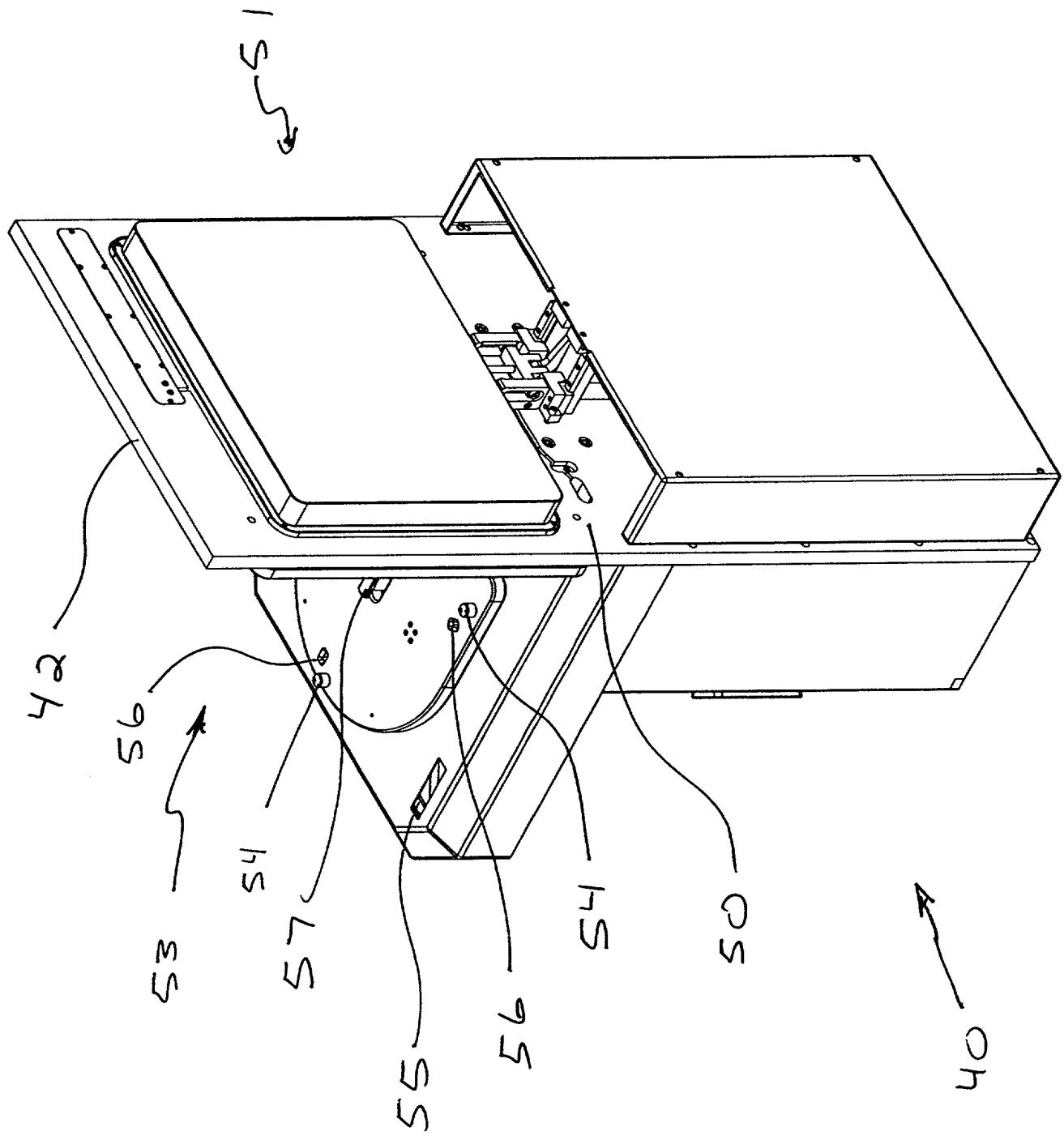
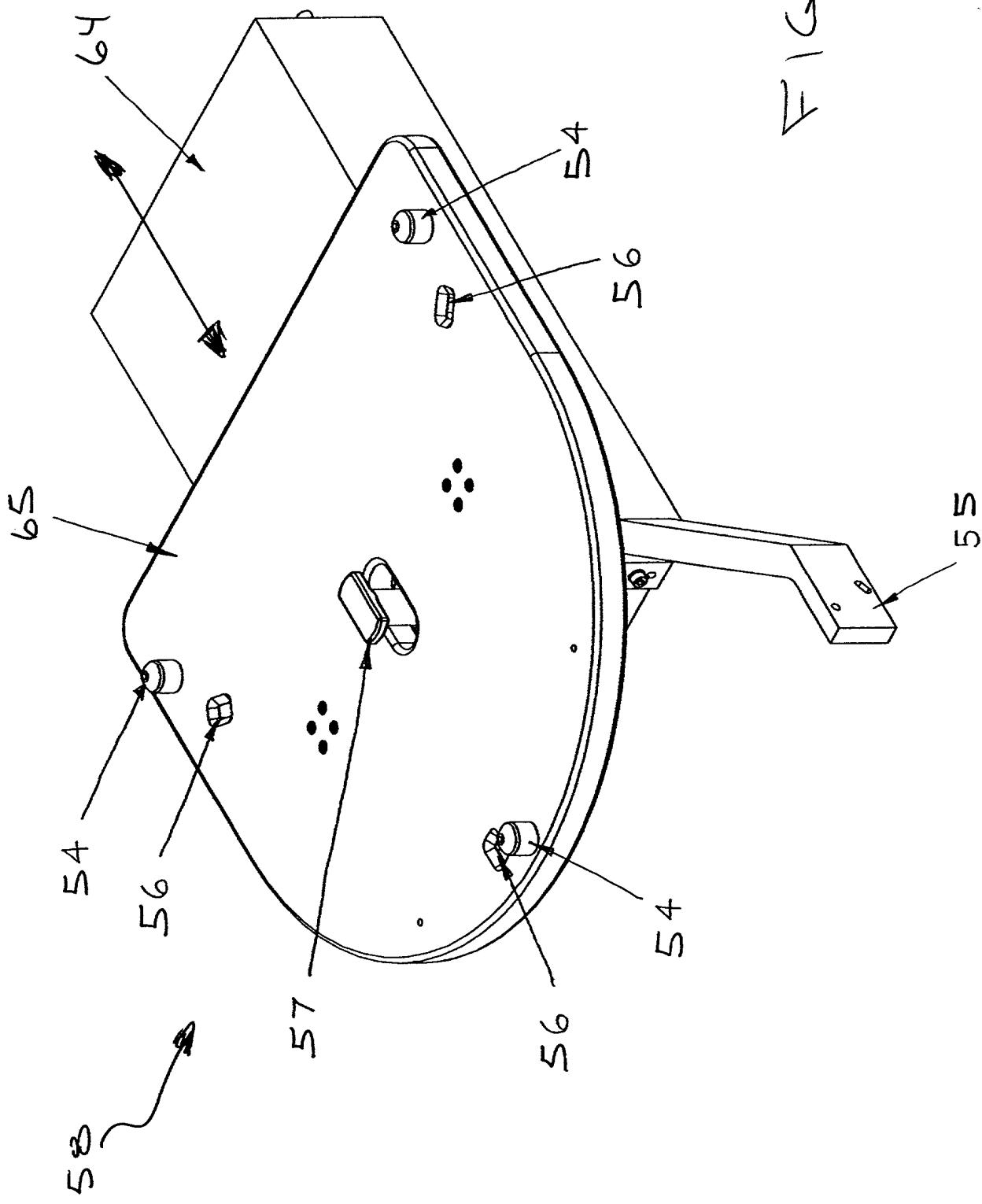


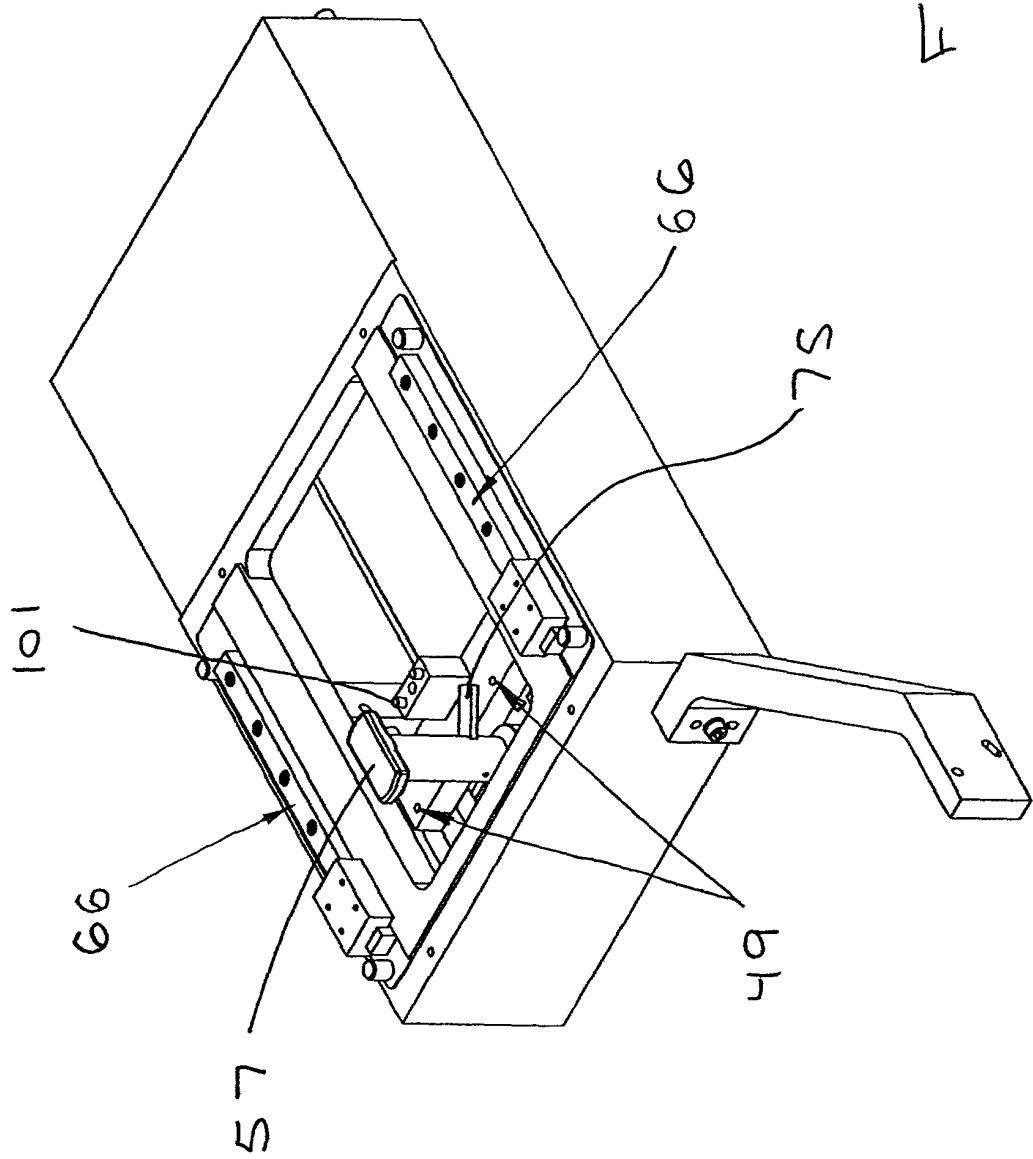
FIG. 4





Line. Apparatus and Methods for  
Semiconductor Wafer Processing Equipment  
Inventor(s): Soucy et al.  
Serial No. Not Yet Assigned  
Docket No. APE-001 Atty: John V. Forcier  
Express Mail No. EL653444577US

SB 510



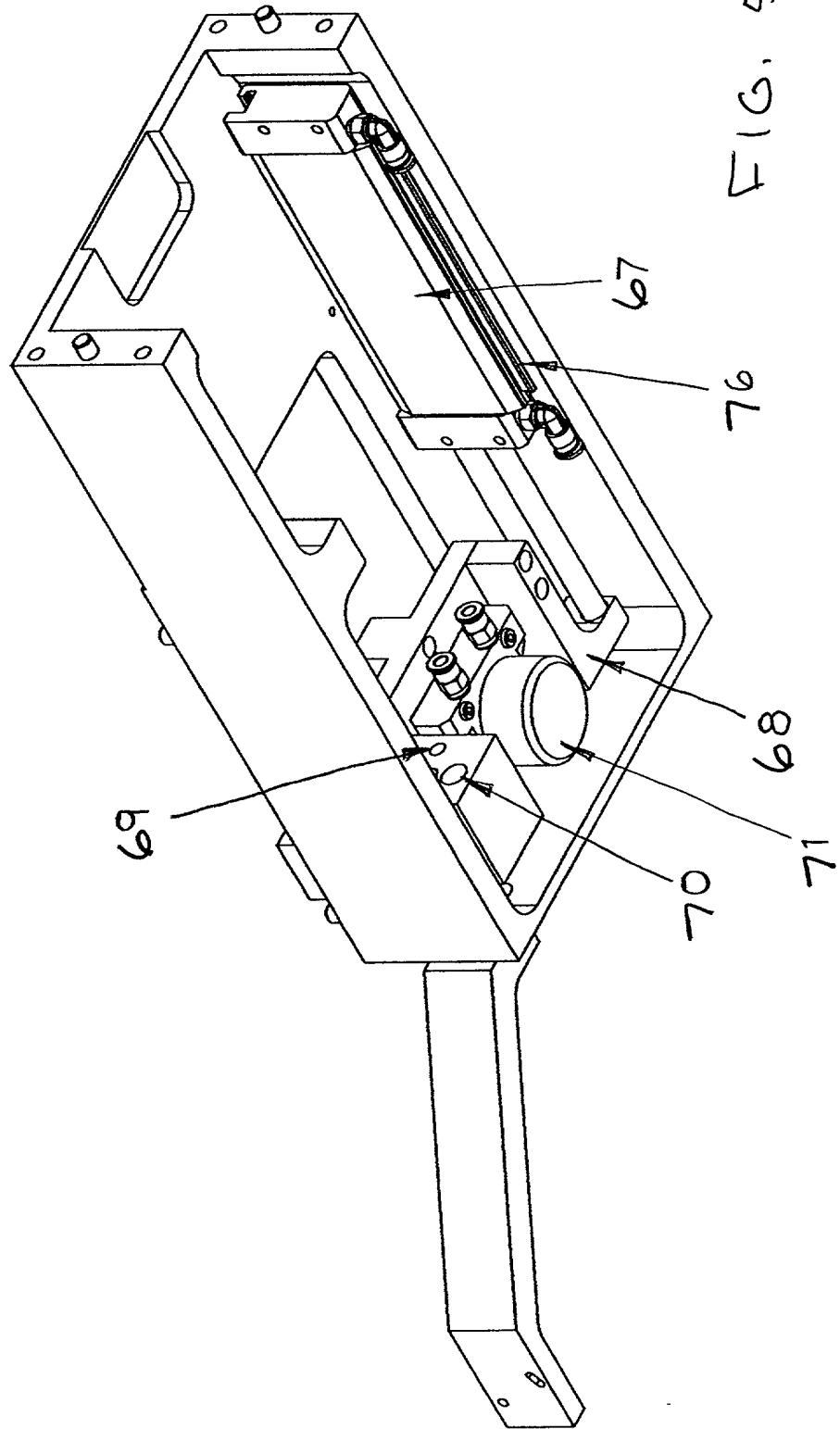
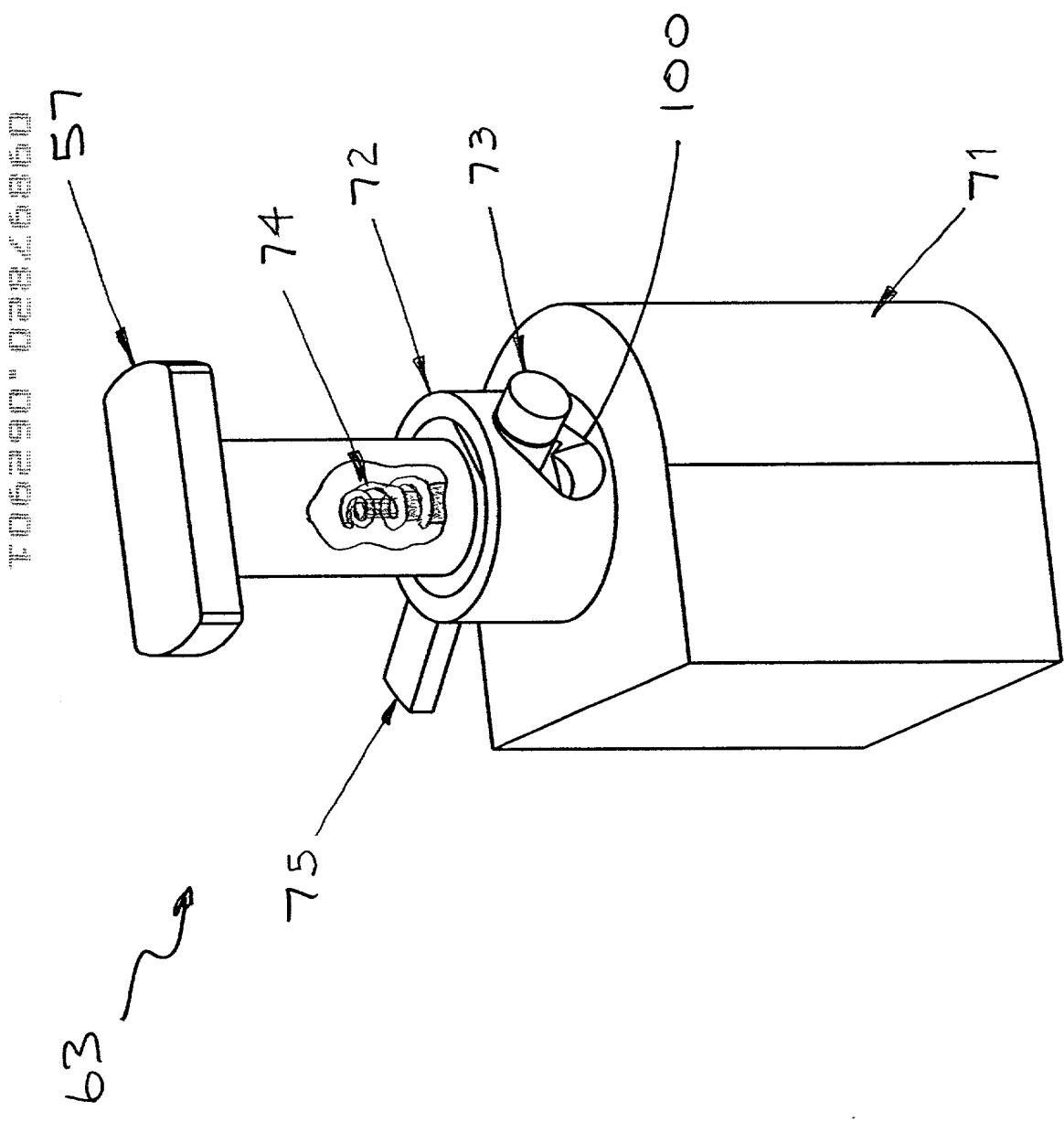


FIG. 5D



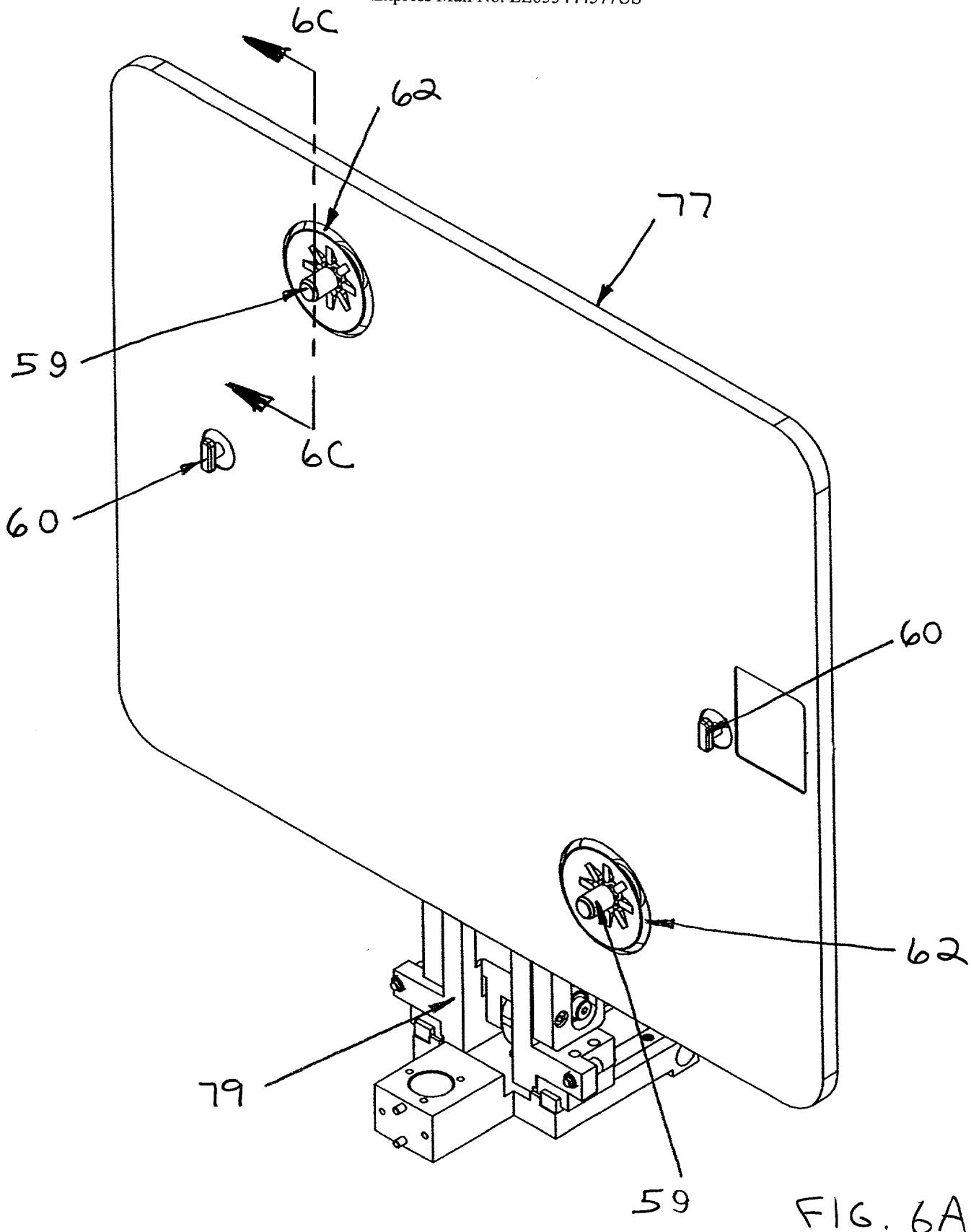


FIG. 6A

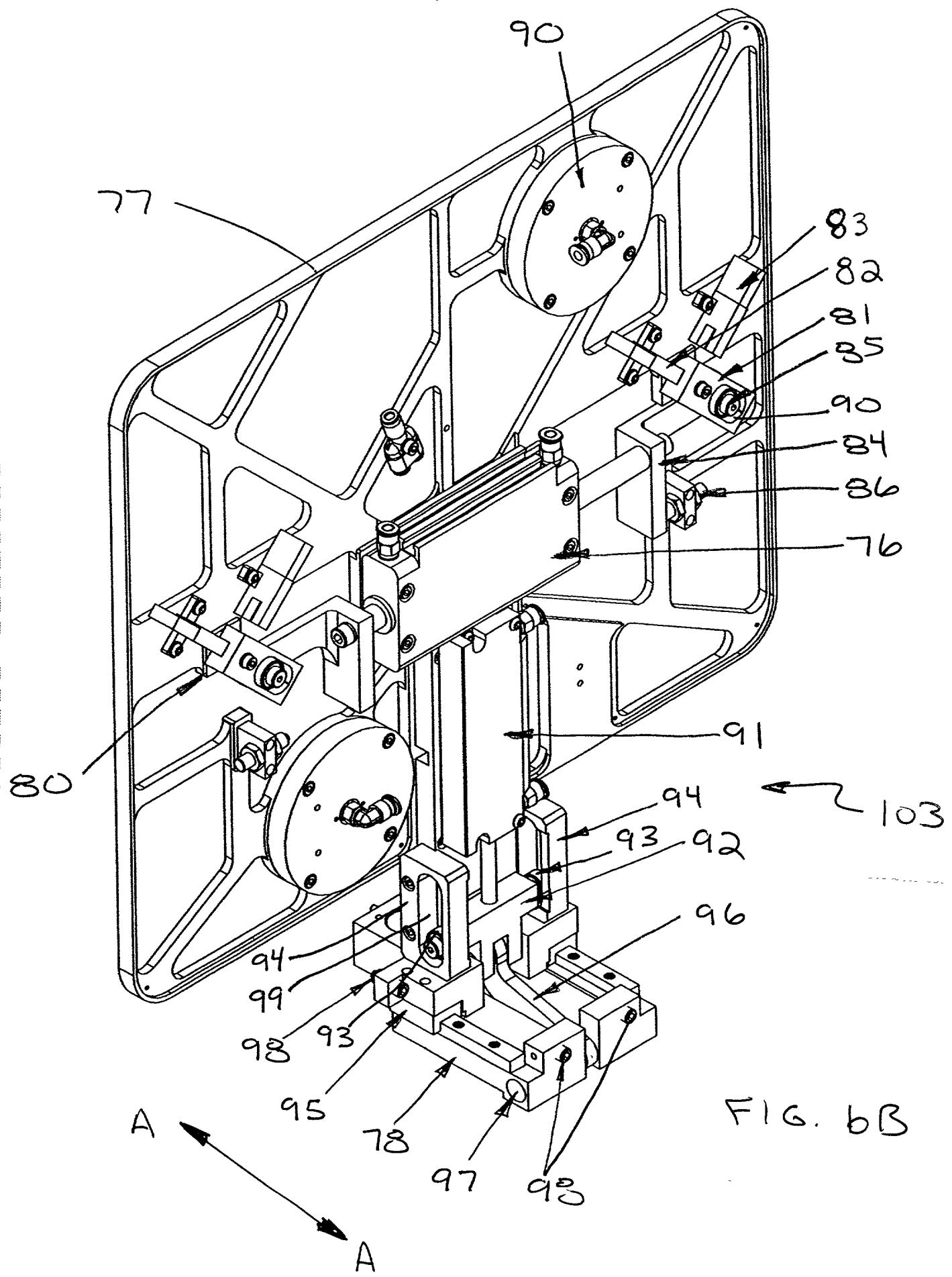
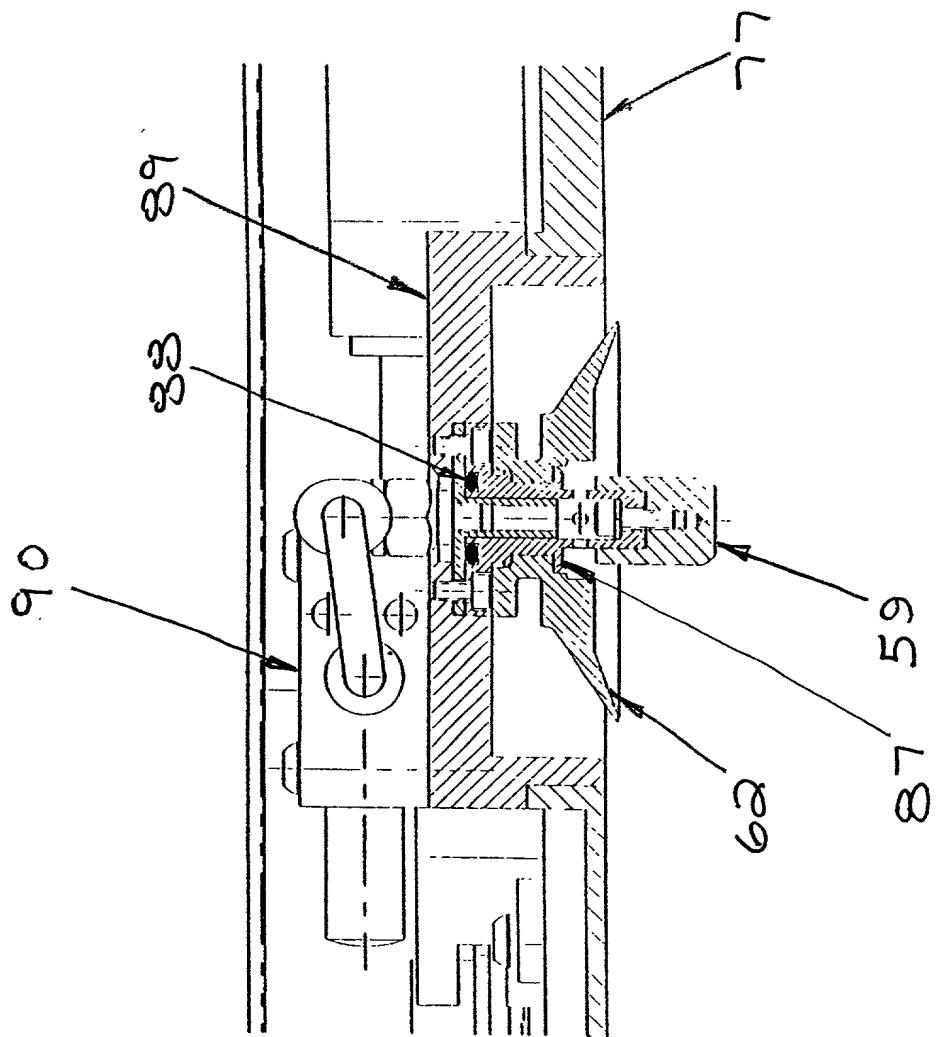


FIG. 6C



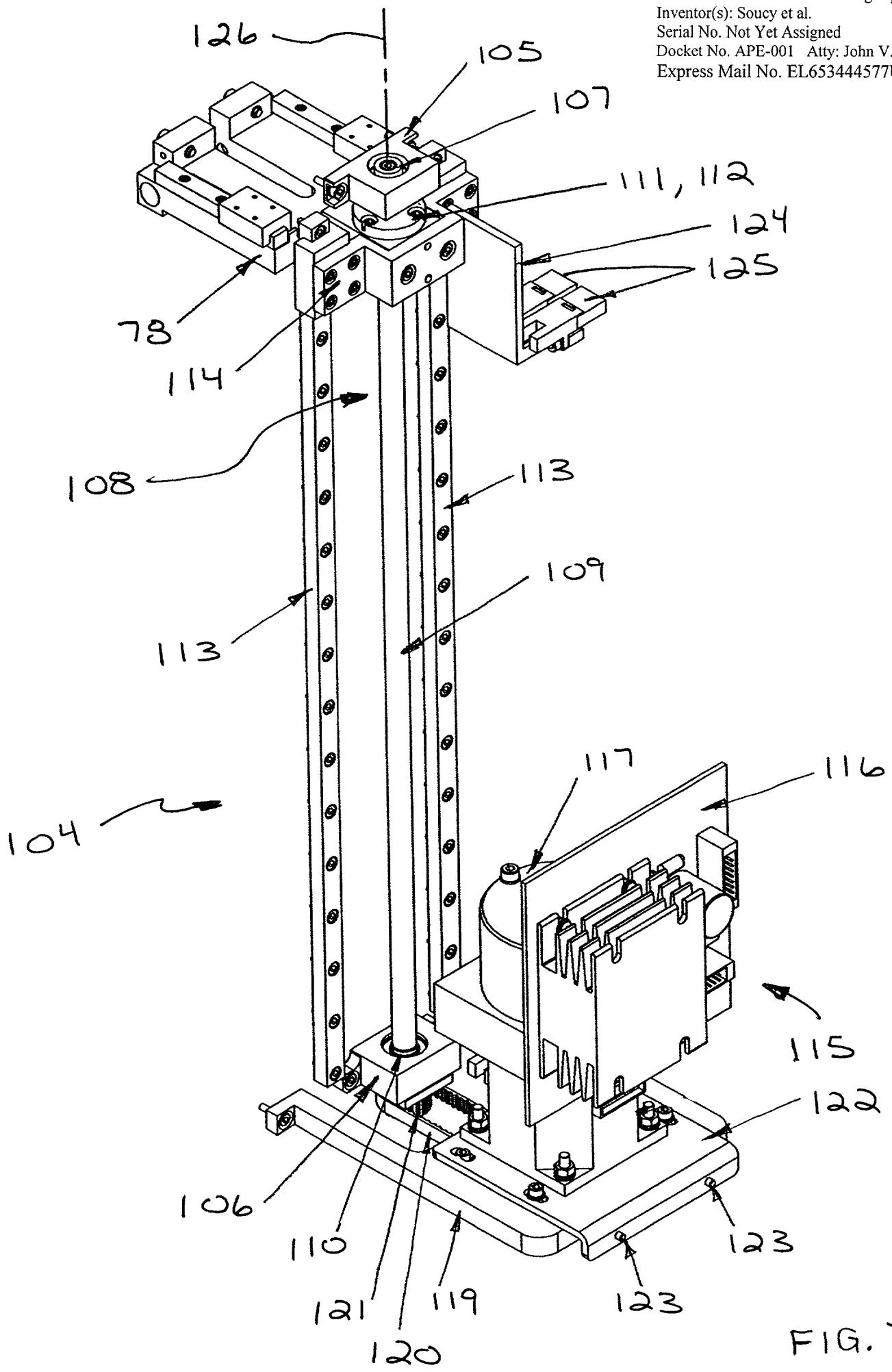


FIG. 7

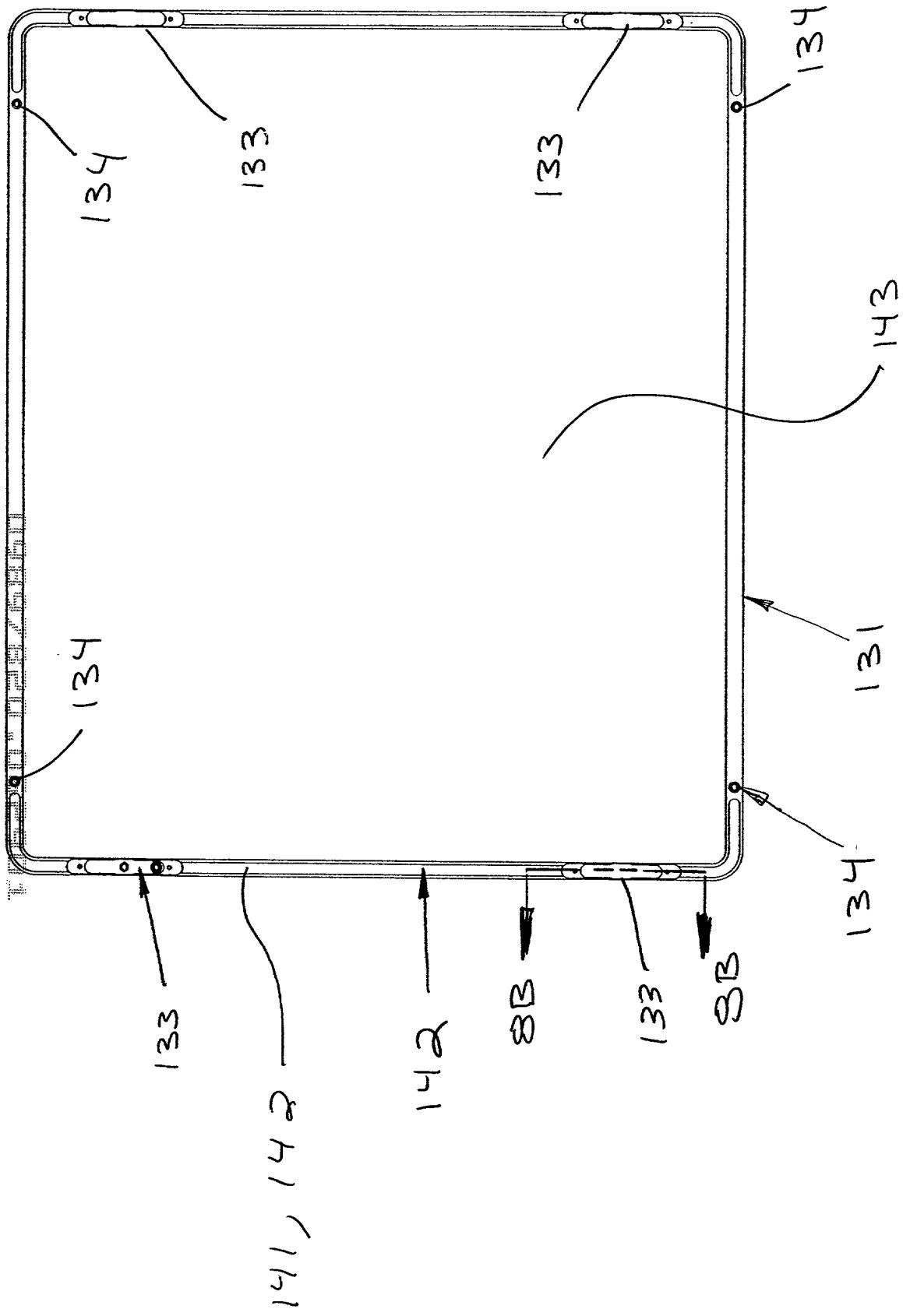
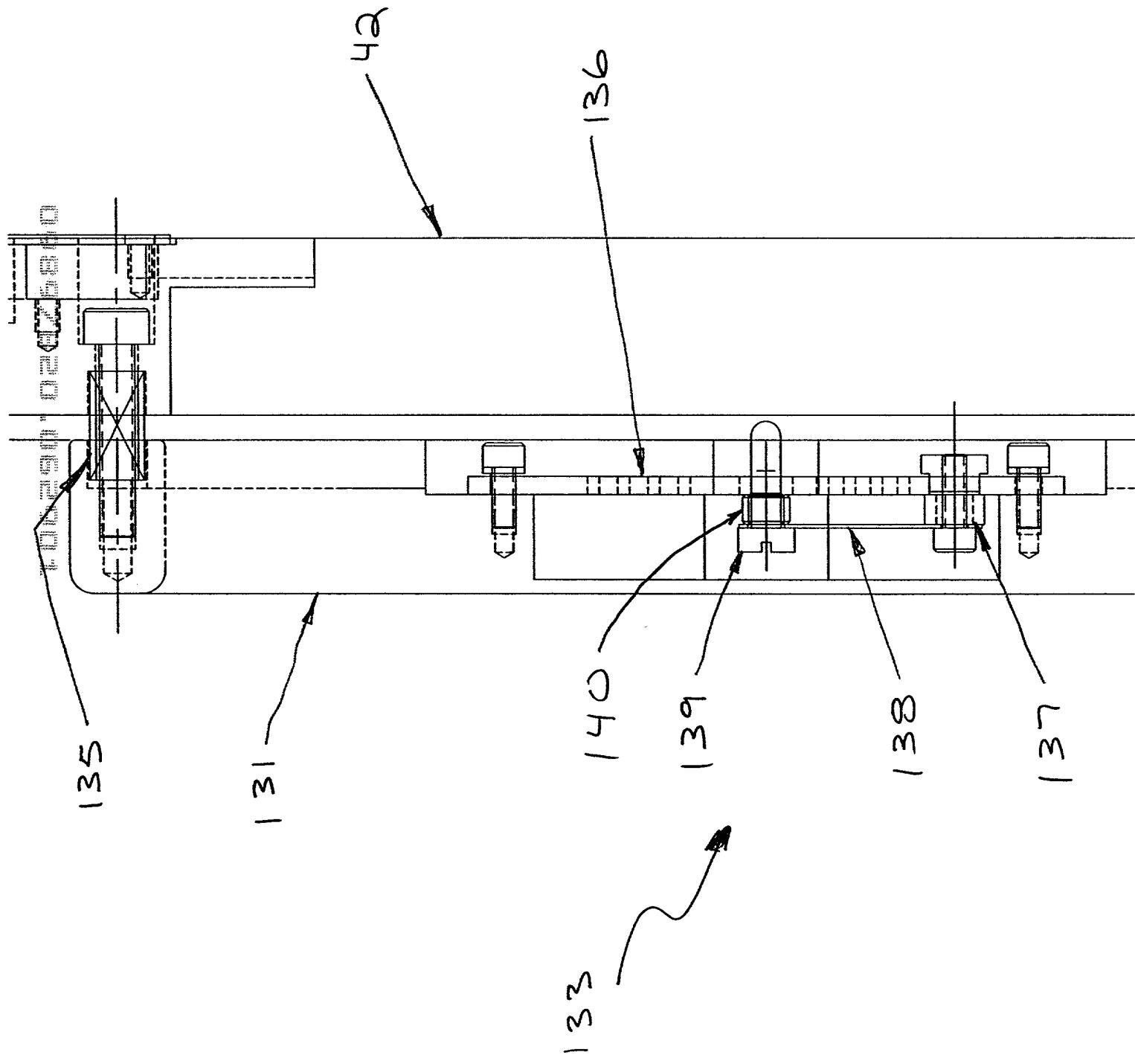


FIG. 2A

Fig. 8B



Title: Apparatus and Methods for  
Semiconductor Wafer Processing Equipment  
Inventor(s): Soucy et al.  
Serial No. Not Yet Assigned  
Docket No. APE-001 Atty: John V. Forcier  
Express Mail No. EL653444577US

## FIG. 9 A

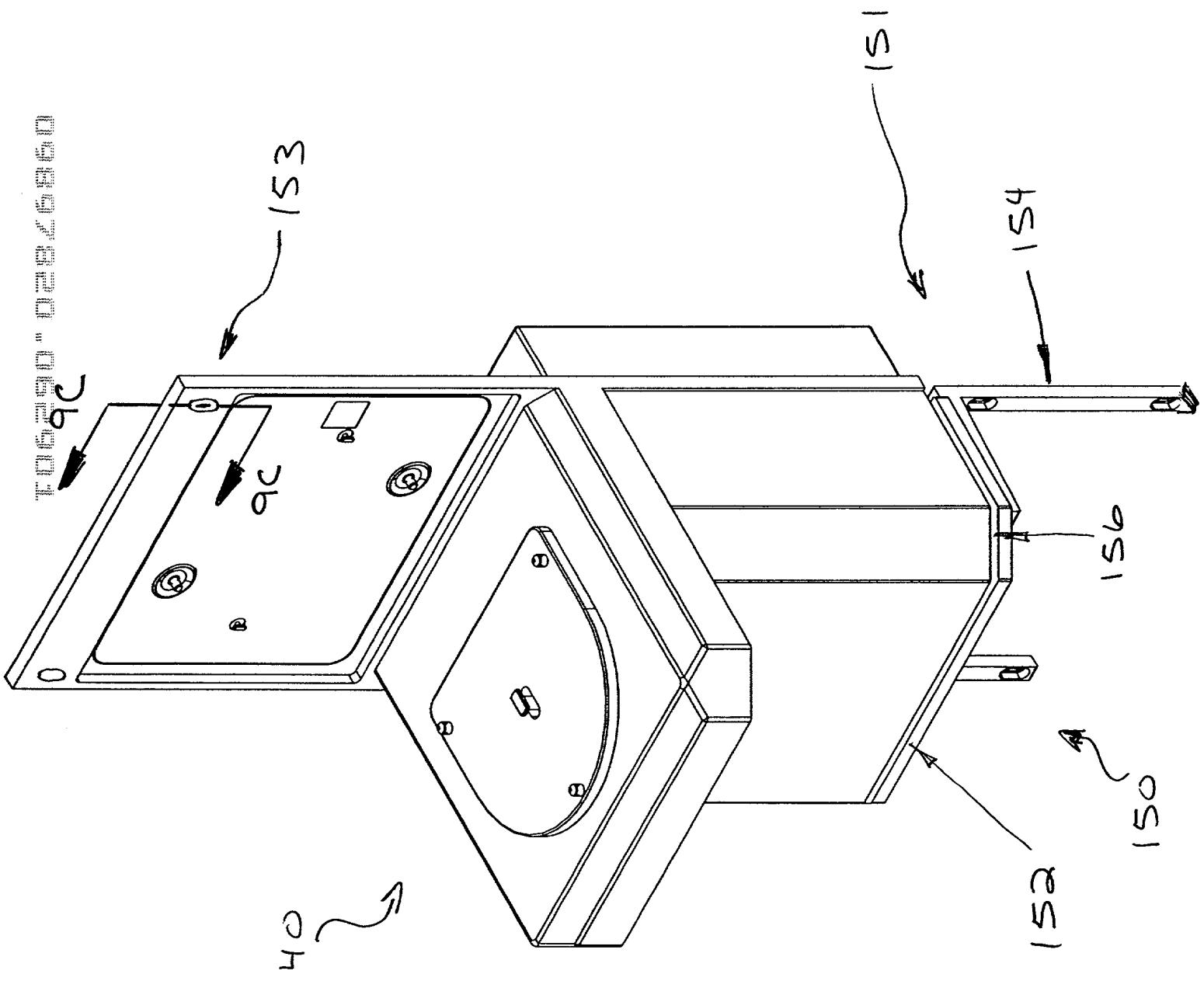
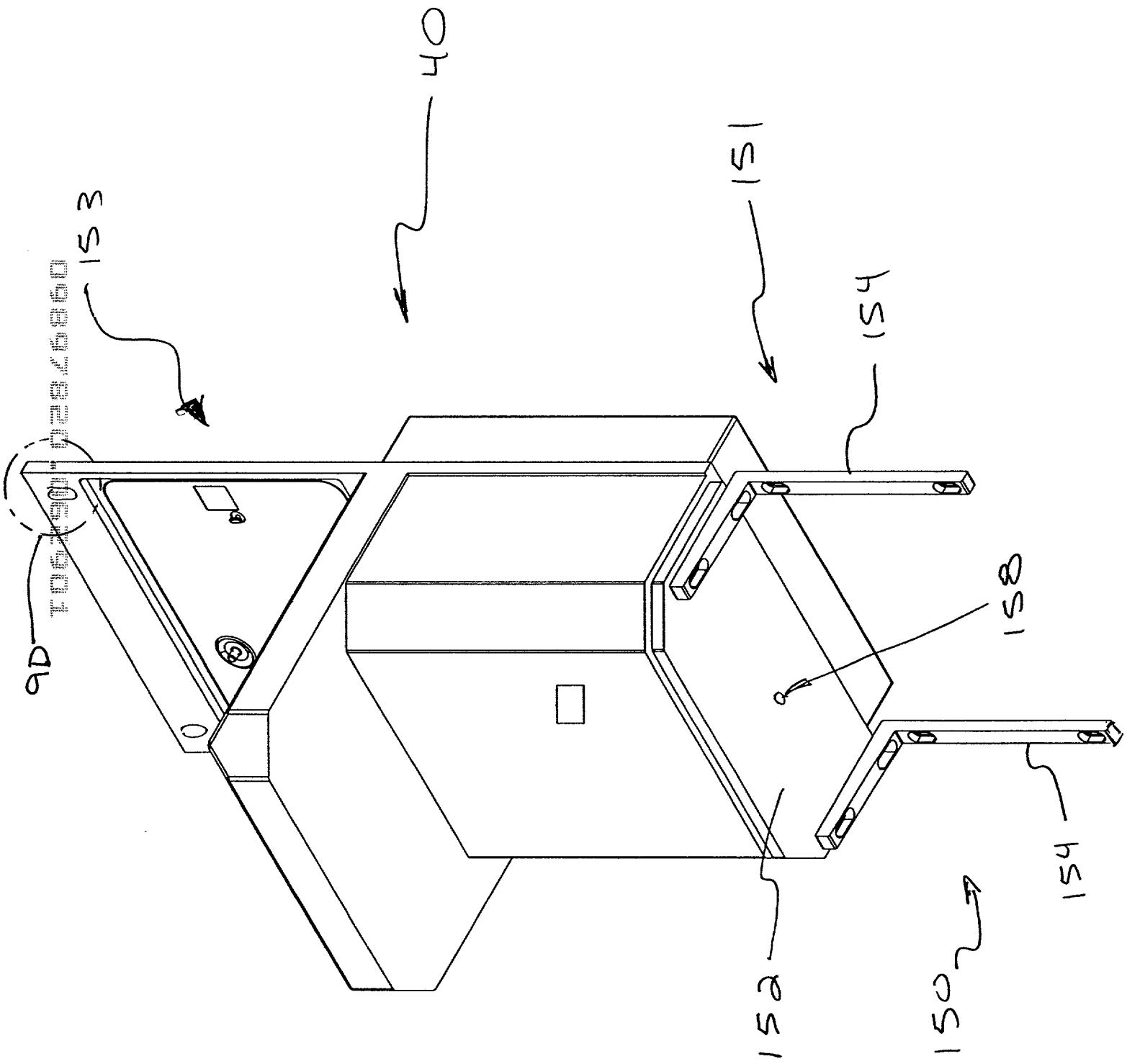


FIG. 9B



卷之五

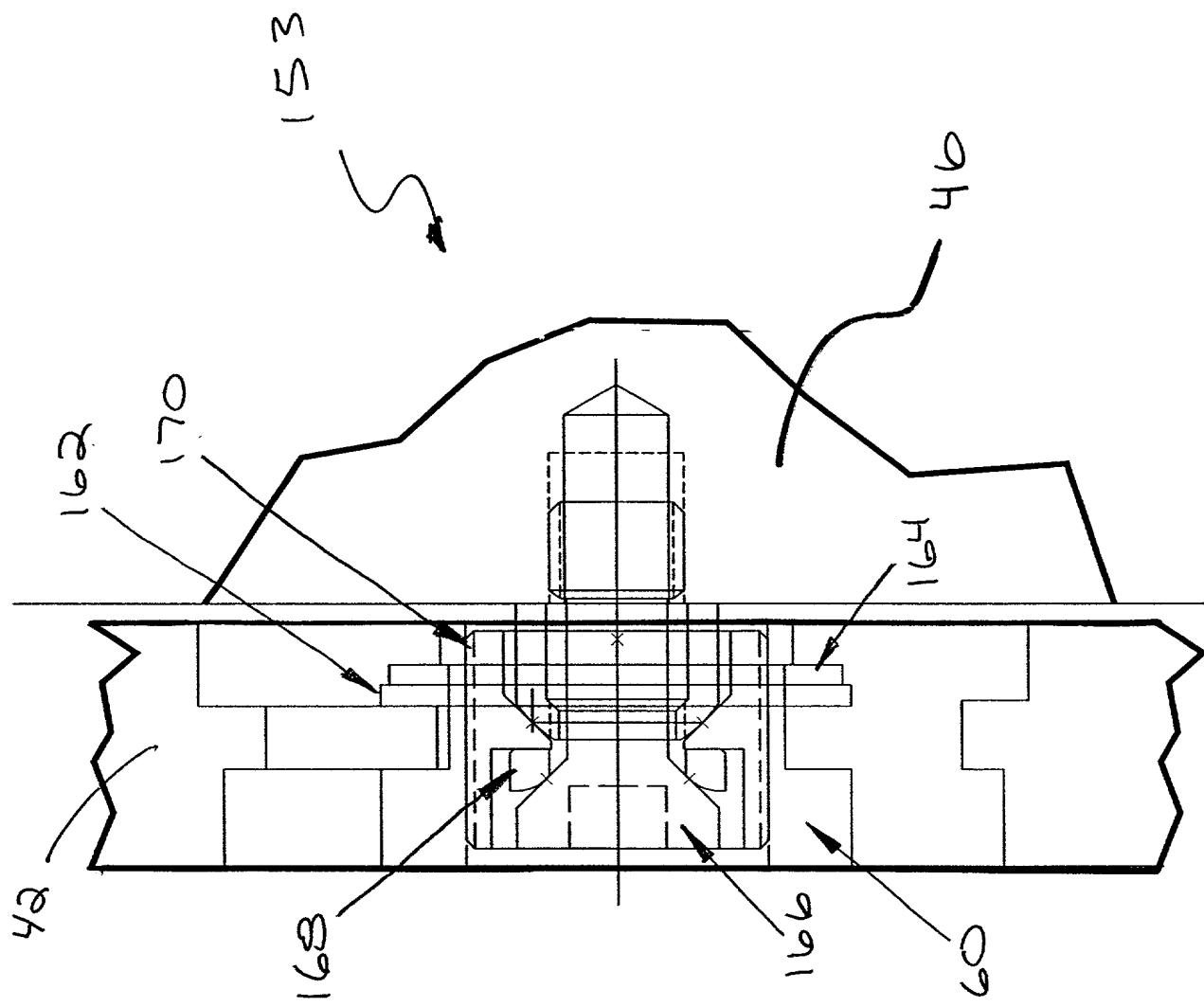
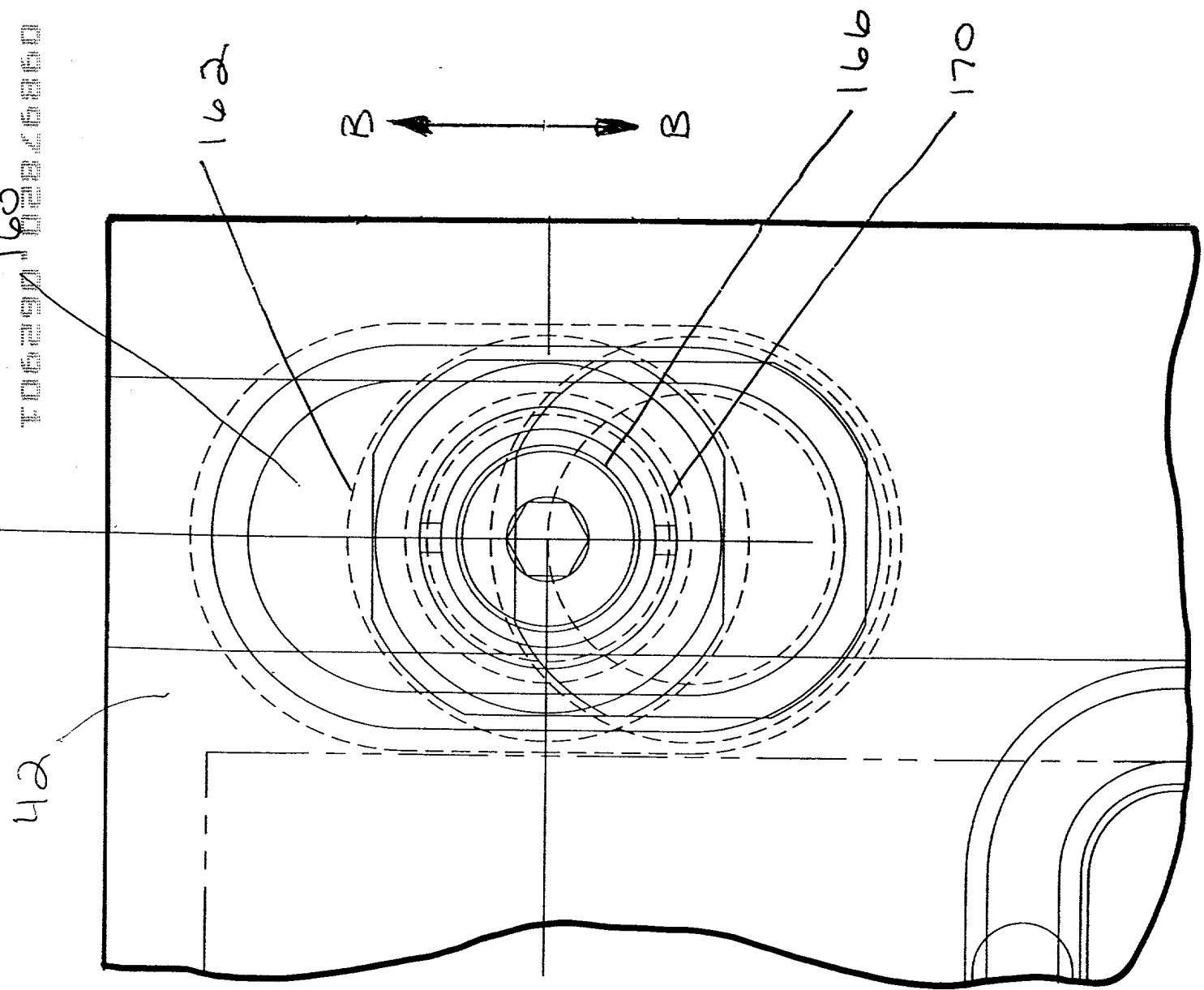
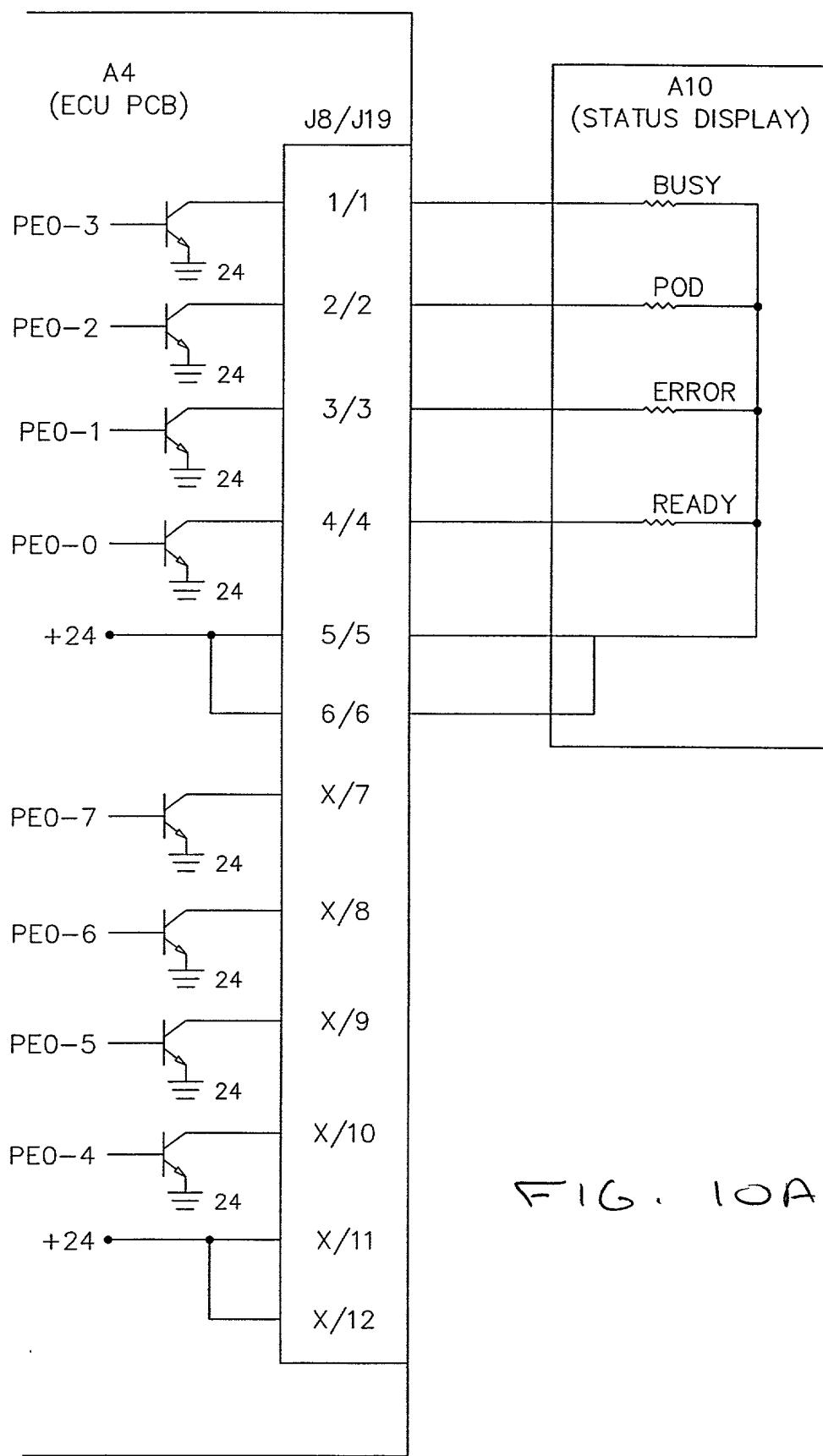


FIG. 9D





BULKHEAD

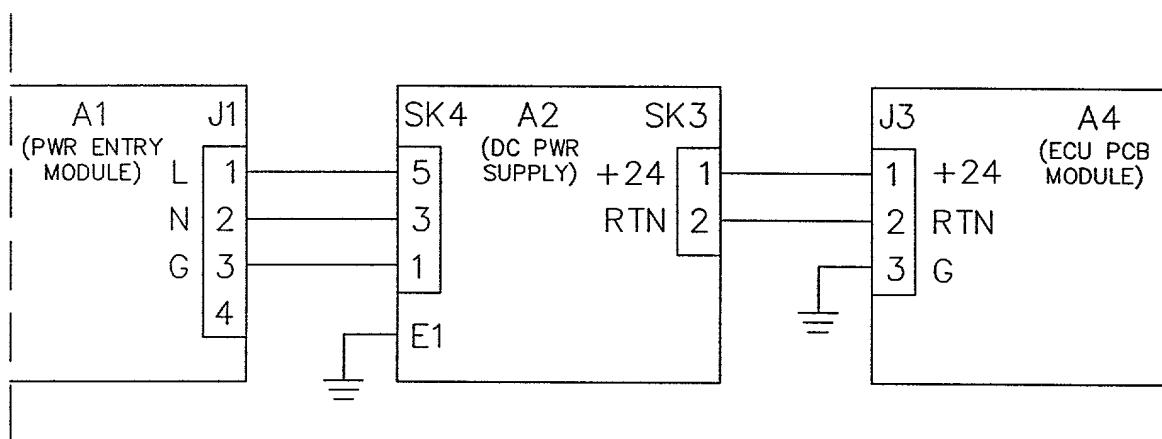


FIG. 10B

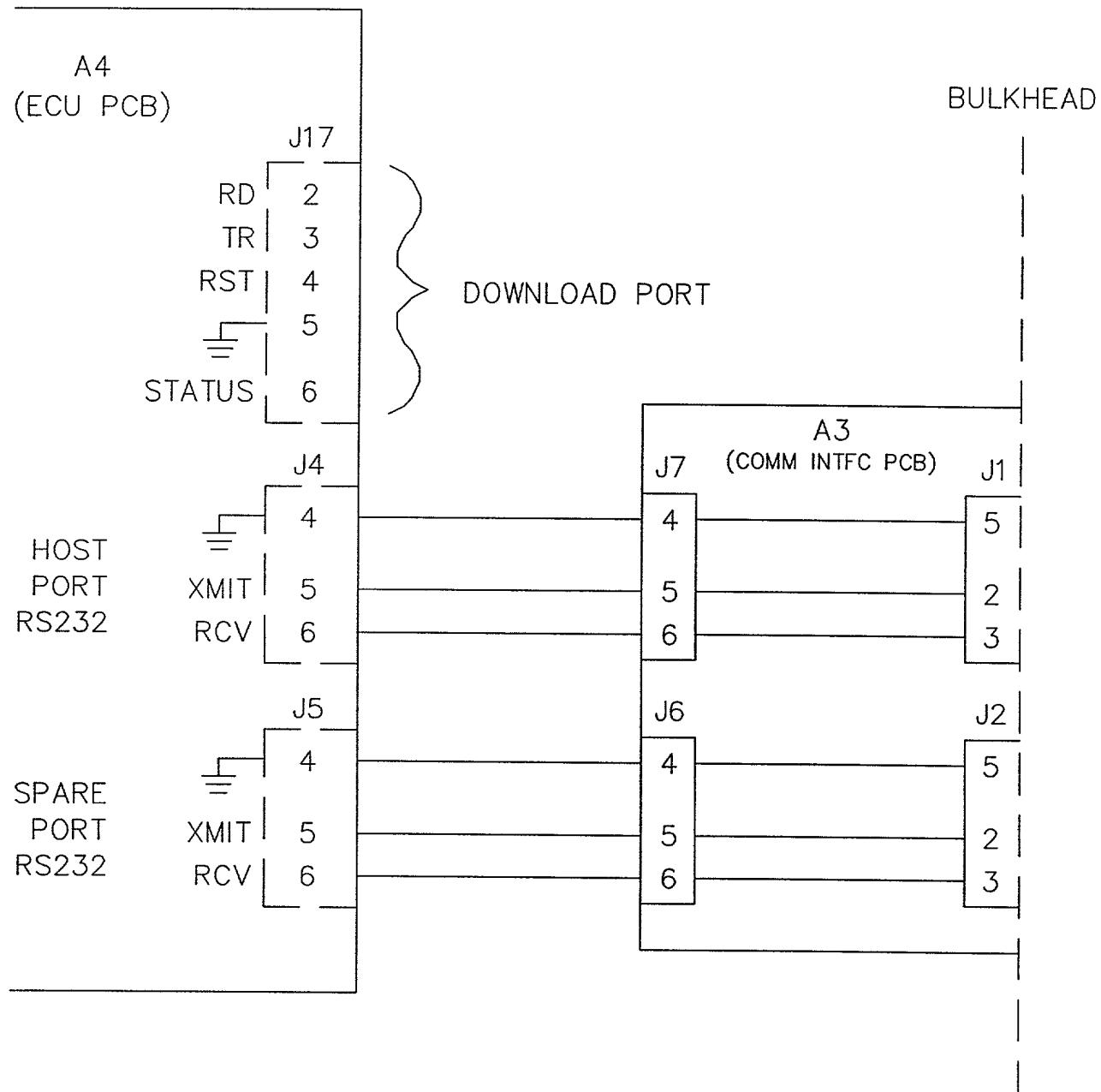


FIG. 10C

A5  
 (PNEUMATIC INTERFACE)

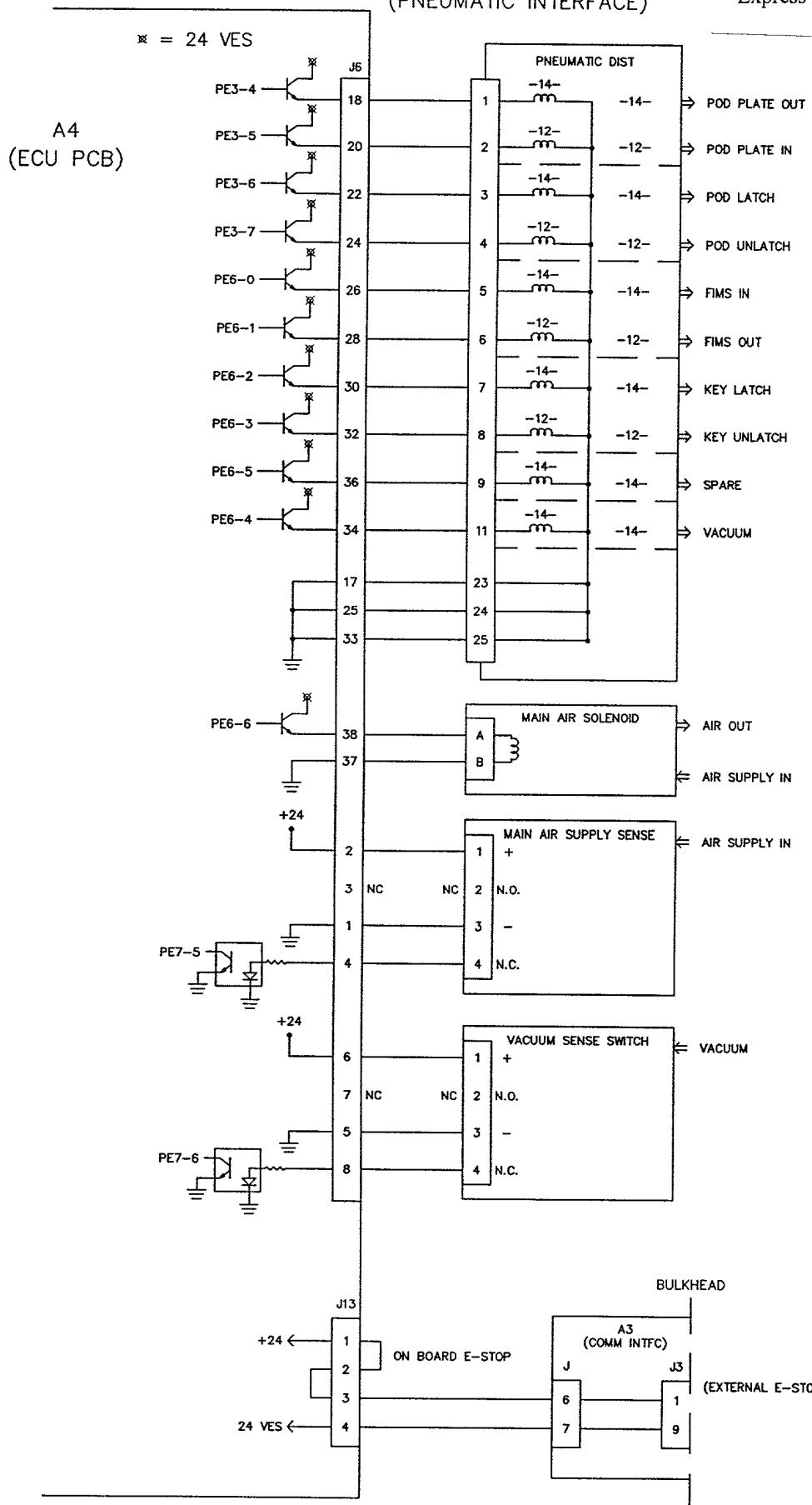


FIG. 10D

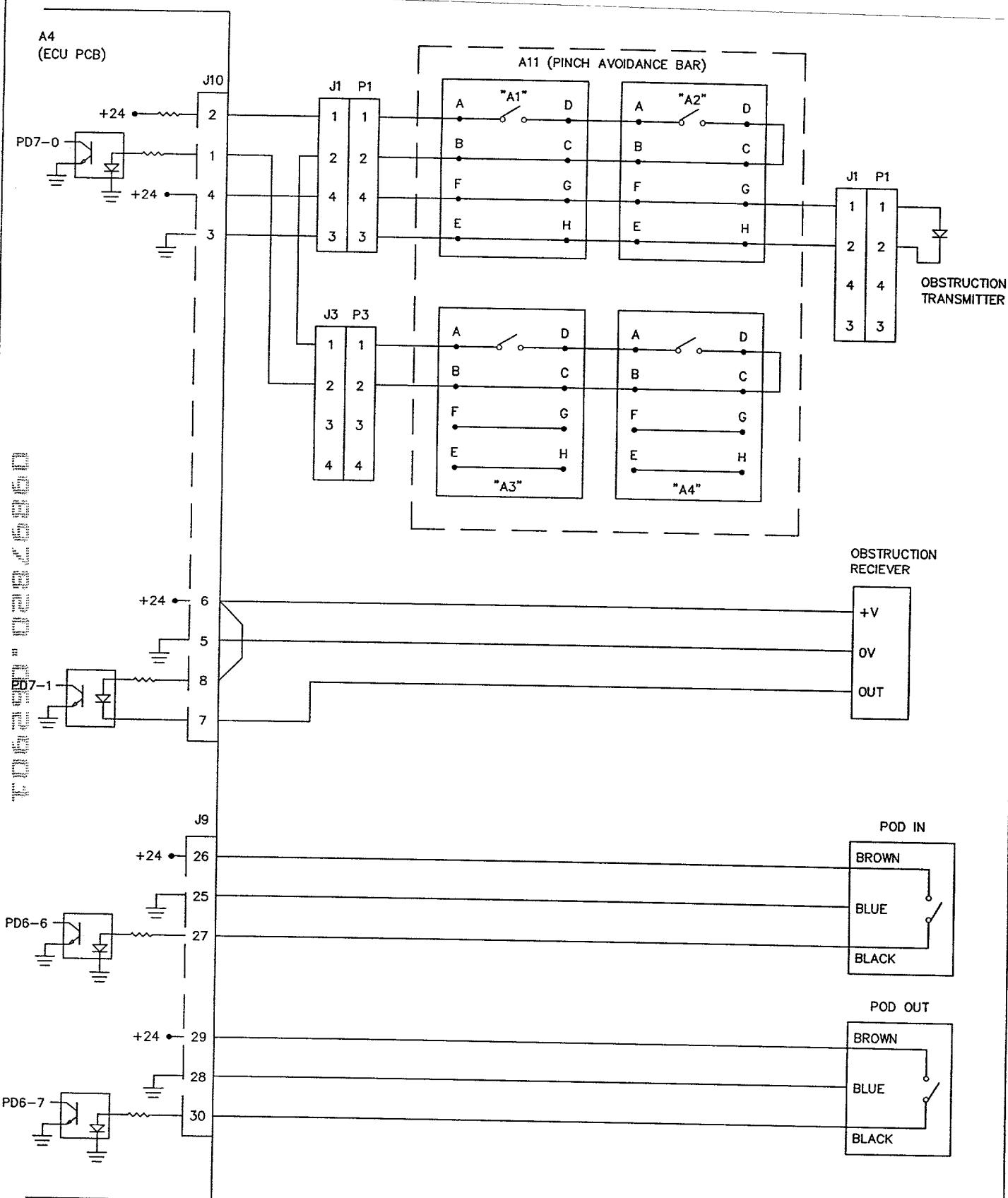


FIG. 10E

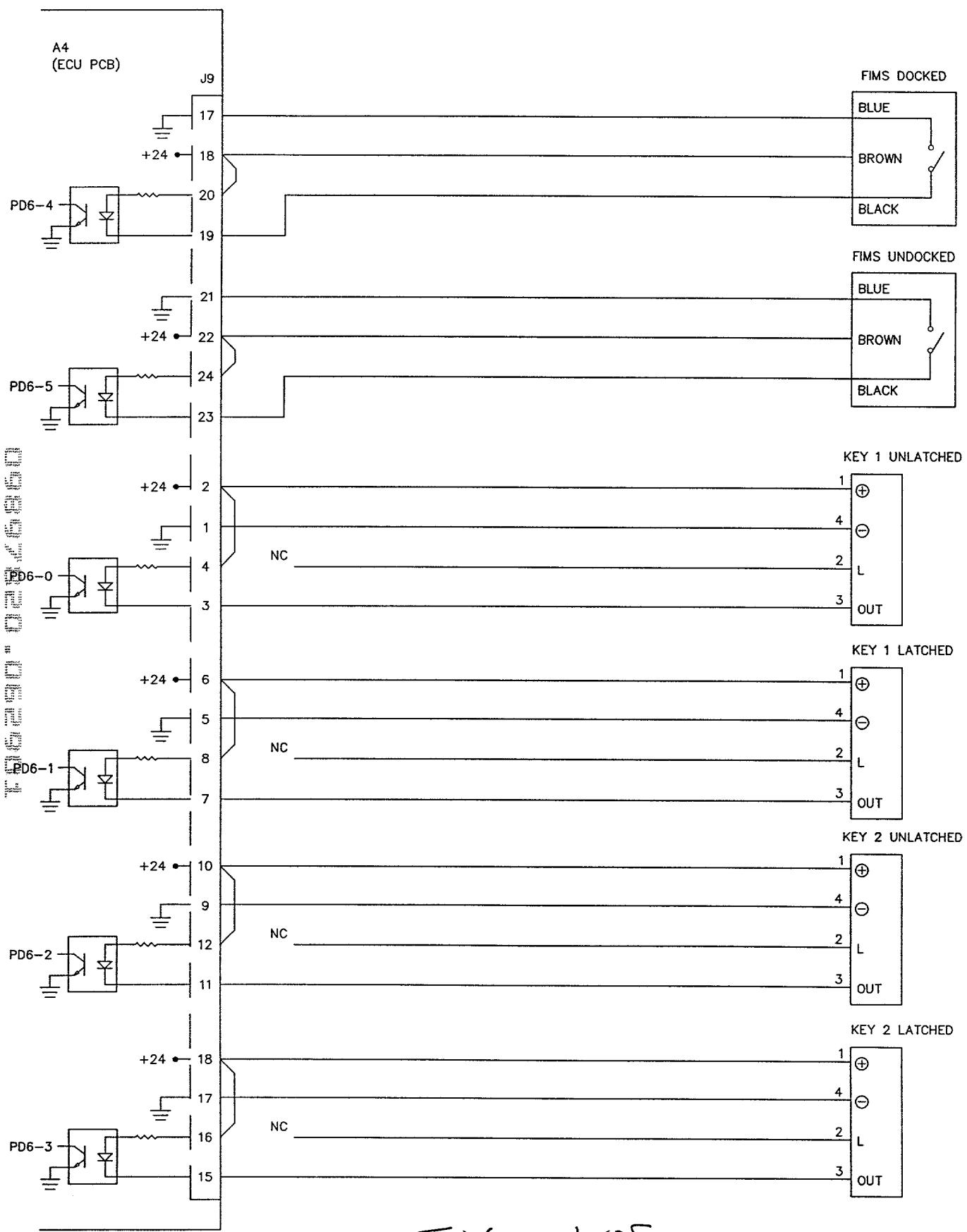


FIG. 10F

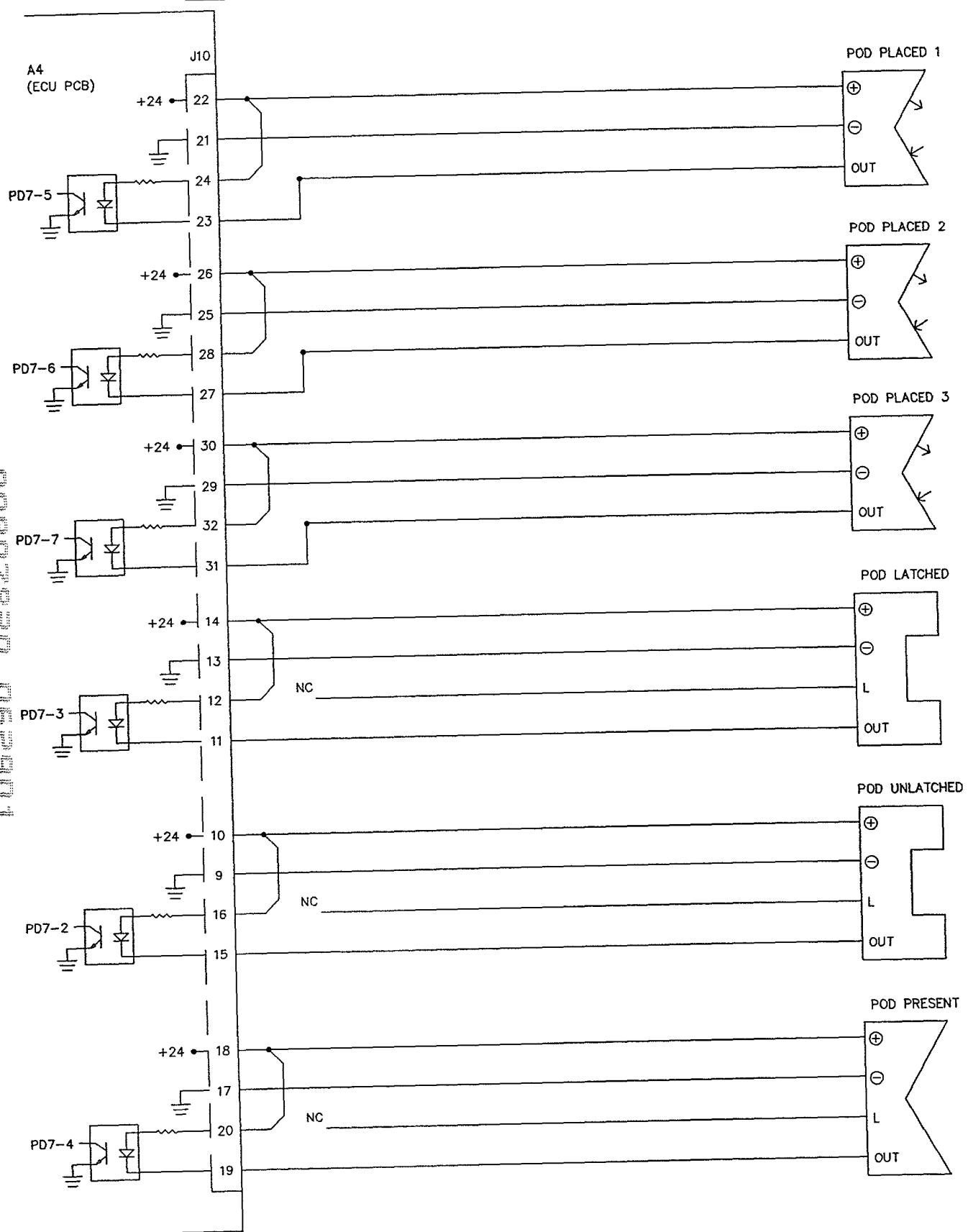


FIG. 10G

